

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18
Stylesheet Version v18.0

Title of Invention

METHOD FOR IMAGE REVERSAL OF IMPLANT RESIST
USING A SINGLE PHOTOLITHOGRAPHY EXPOSURE
AND STRUCTURES FORMED THEREBY

Application Number: 10/664,009

Confirmation Number:

First Named Applicant: Steven Holmes et al.

Attorney Docket Number:

Search string: (6221562 or 6358856 or 6372412 or 6448164 or 6489191).pn.

US Patent Documents

Note : Applicant is not required to submit a paper copy of cited US Patent Documents

Init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
T01	1	6221562	2001-04-24	Boyd et al.			
T01	2	6358856	2002-03-19	Lyons et al.			
T01	3	6372412	2002-04-16	Hakey et al.			
T01	4	6448164	2002-09-10	Lyons et al.			
T01	5	6489191	2002-12-03	Shao et al.			

Signature

Examiner Name	Date
Quincy	12/12/03